

A METHOD FOR DETECTING DEFECTS IN A
MATERIAL AND A SYSTEM FOR ACCOMPLISHING THE SAME

ABSTRACT OF THE DISCLOSURE

The present invention provides a method for detecting defects in a material and a system for accomplishing the same. The method includes obtaining an image of at least a portion of a material's surface and converting the image into an intensity profile. The method further includes determining a defect in the material's surface from the intensity profile. In one exemplary embodiment, the image is an electron image obtained using a scanning electron microscope. The method may further be used to determine a defect density in the material's surface.